

End-Effector Accessory

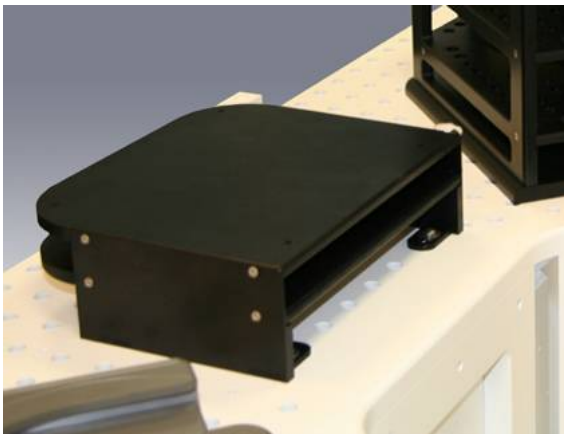


End-Effector Change Station - **mECS**

The end-effector change station is designed to provide a fully automated changing of the end-effector during the work process.

Features

- different end-effector sizes (6"/8")
- storing of up to six end-effectors

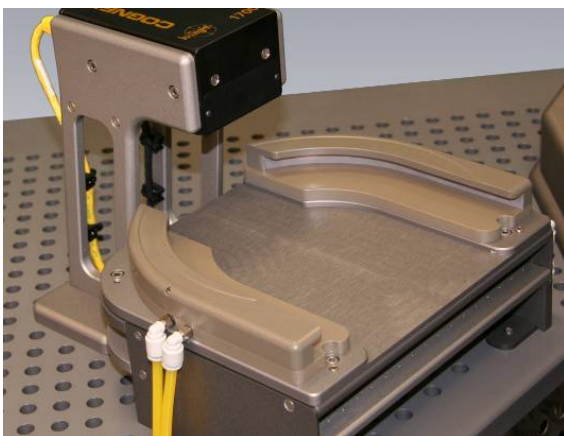


End-Effector Cleaner - **mEC**

The end-effector cleaner is designed for fully automated cleaning of end-effectors in the course of exchange at the *end-effector change station*.

Features

- different end-effector sizes (6"/8")
- cleaning with CDA or N₂
- optional with *transfer station* for throughput optimization



Transfer Station - **mTS**

The transfer station is designed to store a wafer temporarily while e.g. the robot takes a different end-effector for further process.

Features

- different wafer sizes (6"/8")
- storing of a wafer
(e.g. change back side to front side handling)
- optional with OCR reader and/or *end-effector cleaner*

Errors expected. We reserve the right to change technical specifications without prior notice.
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